



PATENT

Attorney Docket No. 02887.0270-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Tadashi MITSUI

Application No.: 10/807,187

Filed: March 24, 2004

For: PATTERN MEASURING
APPARATUS, PATTERN
MEASURING METHOD, AND
MANUFACTURING METHOD OF
SEMICONDUCTOR DEVICE

Group Art Unit: 2624

Examiner: David RASHID

Confirmation No.: 3737

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

In reply to the Office Action mailed January 17, 2008, the period for response having been extended to July 17, 2008, by a Petition for Extension of Time of three months and fee payment filed concurrently herewith, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks follow the amendment section of this paper.

07/18/2008 RMEBRAHT 00000042 060916 10007187

01 FC:1201 1260.00 DA
02 FC:1202 300.00 DA